



Inventor: Kie Y. Ahn et al.
Title: A Dielectric Layer Forming Method and Devices Formed Therewith
Assignee: Micron Technology, Inc.
Docket No. MI22-1534

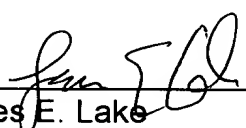
INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR §1.56.
Copies of documents listed on the Form PTO-1449 are enclosed.
No admission is made regarding whether all the submitted references are prior art.

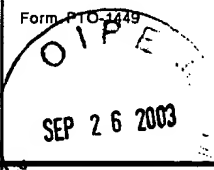
Respectfully submitted,

Dated: 26 Sep 2003

Attorney: 
James E. Lake
Reg. No.: 44,854

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Form PTO-1449 		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-1534		SERIAL NO. 09/881,408	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Kie Y. Ahn, et al			
				FILING DATE June 13, 2001		GROUP 2814	
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,544,875	04/2003	Wilk			
	AB	6,573,197	06/2003	Callegari			
	AC	2001/0021589	09/2001	Wilk			
	AD	2002/0048910	04/2002	Taylor et al			
	AE	2003/0027360	02/2003	Hsu			
	AF	2002/0094643	07/2002	Solomon et al			
	AG	2002/0100946	08/2002	Muller et al			
	AH						
	AI						
	AJ						
	AK						
	AL						
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
	AM						
	AN						
	AO						
	AP						
	AQ						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR						
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